



Patent Application No. 10/712,196
Docket No. JSF02-0004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

5 Applicant(s): Chang-Feng Wan) Art Unit: 2811
Serial No.: 10/712,196~~6~~)
10 Filed: 05/09/2002) Examiner: Shouxiang Hu
For: **SYSTEM AND METHOD OF FABRICATING MICRO CAVITIES**

Director of the US Patent and Trademark Office
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AMENDMENT

In response to the Office Action dated 05 May 2005, in
response to communication filed on 25 February 2005. Please
5 amend the above-identified patent application as follows:

In the figures

Please find attached figures for insertion.
10

In the claims

Please withdraw claims 22-27 from consideration as
claims pursuant to Examiner's restriction requirement.
15

Please amend the claims as follows:

1. (Currently amended)

A method of manufacturing a plurality of micro
20 enclosures on a substrate wafer, comprising steps of:

(1) bonding a cap wafer to said substrate wafer with
an adhesive layer;

~~(2) thinning said cap wafer to desired thickness;~~